

參考文獻

- [1] 朱文彬、吳平耀，"抗反射膜技術解析"，工業材料，第 195 期，P.148-155，92 年 3 月。
- [2] 葉仰哲，"抗反射膜市場潛力調查"，IEK 市調，94 年 9 月。
- [3] Y. Kanamori, et al, "Broadband antireflection gratings fabricated upon silicon substrates", *Opt. Lett.*, 24, pp.1422-1424, 1999.
- [4] J. Hiller, et al, "Reversibly erasable nanoporous antireflection coating from polyelectrolyte multilayers", *Nature Materials*, 1, pp.59-63, 2002.
- [5] M. Ibn-Elhaj and M. Schadt, "Optical polymer thin films with isotropic and anisotropic nano-corrugated surface topologies", *Nature*, 410, pp.796-799, 2001.
- [6] H. A. Macleod, *Thin-film Optical Filters*, 2nd edition, McGraw-Hill, York, pp.5-156, 1989.
- [7] D. Chen, et al, "Anti-reflection (AR) coating made by sol-gel process: A review", *Solar Energy Materials & Solar Cells*, 68, pp.313-336, 2001.
- [8] S. Bäumer, "Handbook of Plastic Optics" (Wiley-VCH, 2005).
- [9] J. E. Green, "Low energy ion bombardment during film deposition from the vapor phase: effects on microstructure and microchemistry", *Solid State Technol.* 14, pp.115-122, 1987.
- [10] S. Mohan and M. G. Krishna, "A review of ion beam assisted deposition of optical thin films", *Vacuum* 46, pp.645-659, 1995.
- [11] S. Pongratz and A. Zöller, "Plasma ion assisted deposition: a promising technique for optical coatings", *J. Vac. Sci. Technol. A* 10, pp.1897-1904, 1992.
- [12] S. Schiller, V. Kirchhoff, N. Schiller, and H. Morgner, "PVD coating of plastic webs and sheets with high rates on large areas", *Surf. Coat. Technol.* 125, pp.354-360, 2000.
- [13] V. Skurat, "Vacuum ultraviolet photochemistry of polymers", *Nucl. Instrum. Methods B* 208, pp.27-34, 2003.

- [14] V. Teixeira, "Mechanical integrity in PVD coatings due to the presence of residual stresses", *Thin Solid Films* 392, pp.276-281, 2003.
- [15] Ulrike Schulz," Review of modern techniques to generate antireflective properties on thermoplastic polymers",*Apl. Opt.* Vol. 45, No. 7, pp.1608-1618, 2006.
- [16] V. Boerner, S. Abbott, B. Bläsi, A.Gombert and W. HoBfeld, "Holographic antiglare and antireflection Films for flat panel display", *SID03 Digest*, pp.68-71, 2003.
- [17] S. Walheim, et al, "Nanophase-Separated Polymer Films as High-Performance Antireflection Coatings", *Science*, 283, pp.520-522, 1999.
- [18] P.B.Clapham, M. C. Hutley, " Reduction of lens reflexion by the moth eye principle ", *Nature*.244, pp.281-282, 1973.
- [19] S. J. Wilson, M. C. Hutley, "The optical properties of moth eye antireflection surfaces", *Optica Acta*.29, pp.993-1009, 1982.
- [20] M. G. Moharam and T. K. Gaylord, "Rigorous coupled-wave analysis of planar-grating diffraction", *J. Opt. Soc. Am.*71, pp.811-818, 1981.
- [21] K.Handobas, S, Kirsch, et al, "Reflection properties of nanostructure -arrayed silicon surfaces", *Nanotechnology*,11, pp.161-164, 2000.
- [22] Y. Kanamori, K. Hane, "100 nm period silicon antireflection structures fabricated using a porous alumina membrane mask", *App. Phy. Lett.*78, pp.142-143, 2001.
- [23] Y. Zhaoning, and Y. C. Stephen, " Fabrication of large area subwavelength antireflection structures on Si using trilayer resist nanoimprint lithography and liftoff ", *J. Vac. Sci. Technol. B*.21, pp.2874-2877, 2003.
- [24] 吳平耀, "抗反射膜製造方法介紹", *工業材料*, 第 206 期, P.98-106, 93 年 2 月。
- [25] D. H. Raguin and G. M. Morris, "Antireflection structured surfaces for the infrared spectral region", *Appl. Opt.*32, pp.1154-1167, 1993.

- [26] M. G. Moharam and T. K. Gaylord, "Rigorous coupled-wave analysis of planar-grating diffraction", J. Opt. Soc. Am., 71, pp.811-818,1981.
- [27] M. G. Moharam and T. K. Gaylord, "Diffraction analysis of dielectric surface-relief gratings", J. Opt. Soc. Am., 72, pp.1385-1392, 1982.
- [28] R. C. Enger and K. C. Steven, "Optical elements with ultrahigh spatial-frequency surface corrugations", Appl. Opt., 22, pp.3220 - 3228, 1983.
- [29] T. K. Gaylord, and M. G. Moharam, " Zero-reflectivity high spatial-frequency rectangular-groove dielectric surface-relief gratings", Appl. Opt., 25, pp.4562 - 4567, 1986.
- [30] W. H. Southwell, " Pyramid-array surface-relief structures producing antireflection index matching on optical surfaces", J. Opt. Soc. Am. A, 8, p.549, 1991.
- [31] E. B. Granm, M. G. Moharam, and D. A. Pommet, "Artificial uniaxial and biaxial dielectrics with use of two-dimensional subwavelength binary gratings" J. Opt. Soc. Am. A, 11, 1994, pp.2695-2703.
- [32] 丁效強, "光子晶體抗反射膜研究", 國立中央大學光電科學研究所碩士論文, P.9-12, 94年6月。
- [33] C. H. Hsu, H. C. Lo, C. F. Chen, C. T. Wu, J. S. Hwang, D. Das, J. Tsai, L. C. Chen, and K. H. Chen, "Generally Applicable Self-Masked Dry Etching Technique for Nanotip Array Fabrication", Nano Letters, 4 (3), pp.471-475, 2004.
- [34] 黃逸帆, "奈米針尖陣列之製備及其光學特性之研究", 國立台北科技大學製科所碩士論文, P.37-39, 93年6月。